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# Microoptics



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# Contents

Preface	1
<b>1 From macrooptics to microoptics — an overview</b>	<b>3</b>
1.1 Optics technology	3
1.2 Classification of optical hardware	5
1.3 Optical functions and their implementation	6
1.4 Scope of this book	10
1.5 Organization of the book	10
1.6 Further reading	12
1.7 Acknowledgment	13
<b>2 Optical components with small dimensions</b>	<b>15</b>
2.1 Microlens performance	15
2.1.1 Diffraction limit	15
2.1.2 Aberrations	17
2.1.3 Quality criteria for lens performance	21
2.2 Scaling — from macro- to micro-components	27
2.2.1 Scaling of diffractive and refractive lenses	27
2.2.2 Scaling of prisms	30
2.3 Glossary	32
2.4 List of symbols	33
2.5 Exercises	34
<b>3 Lithographic fabrication technology</b>	<b>37</b>
3.1 Pattern generation	38
3.1.1 Plotting and photoreduction	40
3.1.2 Laser beam writing	40
3.1.3 X-ray and e-beam writing	42
3.1.4 Grey-level masks	47
3.1.5 Special masks	50
3.2 Coating or thin layer deposition	50
3.2.1 Spin coating	51

3.2.2	Physical vapour deposition (PVD) . . . . .	51
3.2.3	Chemical Vapour Deposition (CVD) . . . . .	54
3.3	Alignment and exposure . . . . .	54
3.3.1	Exposure geometry . . . . .	55
3.3.2	Light sources for mask lithography . . . . .	57
3.3.3	Illumination with x-ray (synchrotron) and proton radiation . . . . .	58
3.3.4	Multimask alignment . . . . .	59
3.3.5	Through-wafer alignment . . . . .	61
3.4	Pattern transfer . . . . .	61
3.4.1	Etching . . . . .	63
3.4.2	Laser micromachining — laser initiated ablation . . . . .	68
3.4.3	Mechanical micromachining — diamond turning of microoptical components . . . . .	69
3.4.4	Replication of microrelief structures . . . . .	70
3.4.5	Diffusion — ion-exchange processes . . . . .	73
3.5	Bonding of planar structures . . . . .	73
3.5.1	Flip-chip bonding . . . . .	74
3.5.2	Thermo-anodic bonding . . . . .	76
3.6	Glossary . . . . .	78
3.7	List of new symbols . . . . .	79
3.8	Exercises . . . . .	80
<b>4</b>	<b>Refractive microoptics</b> . . . . .	<b>85</b>
4.1	Surface profile microlenses . . . . .	86
4.1.1	Melted photoresist lenses — reflow lenses . . . . .	86
4.1.2	Microlens fabrication by mass transport mechanisms in semiconductors . . . . .	93
4.1.3	Microlenses formed by volume change of a substrate material . . . . .	94
4.1.4	Lithographically initiated volume growth in PMMA for microlens fabrication . . . . .	96
4.1.5	Dispensed or droplet microlenses . . . . .	99
4.1.6	Direct writing techniques for refractive microoptics . . . . .	100
4.1.7	Grey-scale lithography for ROE fabrication . . . . .	103
4.2	Gradient-index (GRIN) optics . . . . .	104
4.2.1	GRIN rod lenses . . . . .	105
4.2.2	Planar GRIN lenses . . . . .	108
4.3	Microprisms and micromirrors . . . . .	115
4.3.1	Lithography for the fabrication of microprisms . . . . .	116
4.3.2	Micromachining of microprisms using single point diamond turning or embossing . . . . .	119
4.3.3	Anisotropic etching of mirror structures in crystalline materials . . . . .	119
4.4	Glossary . . . . .	121
4.5	List of new symbols . . . . .	122
4.6	Exercises . . . . .	123

<b>5</b>	<b>Diffractive microoptics</b>	<b>129</b>
5.1	Trading spatial resolution for reduced phase thickness . . . . .	129
5.1.1	Blazing and phase quantization . . . . .	129
5.1.2	Alternative quantization schemes for microlenses . . . . .	132
5.1.3	Examples of diffractive optical components . . . . .	134
5.2	Fabrication of diffractive optics . . . . .	134
5.2.1	Multimask processing for kinoform DOEs . . . . .	135
5.2.2	Fabrication errors for kinoform elements . . . . .	137
5.3	Modelling of diffractive optics . . . . .	139
5.3.1	Approaches to rigorous diffraction theory . . . . .	140
5.3.2	Thin and thick gratings . . . . .	143
5.3.3	Scalar diffraction theory . . . . .	145
5.3.4	Fresnel and Fraunhofer diffraction . . . . .	147
5.3.5	Linear kinoform grating . . . . .	148
5.3.6	Diffractive lenses . . . . .	151
5.3.7	Ray-tracing analysis of diffractive lenses . . . . .	156
5.3.8	Chromatic aberrations of diffractive lenses . . . . .	158
5.3.9	Detour-phase diffractive optical elements . . . . .	158
5.3.10	Polarisation-selective diffractive optical elements . . . . .	161
5.3.11	Holographic optical elements as thick Bragg gratings . . . . .	161
5.3.12	Effective medium theory of zero-order gratings . . . . .	166
5.4	Design of diffractive optical elements . . . . .	167
5.4.1	DOEs optimized for imaging along a tilted optical axis . . . . .	167
5.4.2	Iterative design techniques for DOEs . . . . .	169
5.5	Glossary . . . . .	172
5.6	List of new symbols . . . . .	173
5.7	Exercises . . . . .	174
<b>6</b>	<b>Integrated waveguide optics</b>	<b>181</b>
6.1	Modes in optical waveguides . . . . .	181
6.1.1	Discrete waveguide modes . . . . .	182
6.1.2	Field distribution of the modes . . . . .	184
6.2	Waveguide couplers and beam splitters . . . . .	186
6.2.1	External coupling . . . . .	186
6.2.2	Coupling between waveguides . . . . .	189
6.2.3	3 dB couplers for beam splitting . . . . .	191
6.2.4	Branching waveguides . . . . .	192
6.3	Waveguide optical modulators . . . . .	192
6.3.1	The electro-optic effect . . . . .	192
6.3.2	The electro-optic phase modulator . . . . .	193
6.3.3	Polarisation modulator — dynamic phase retarder . . . . .	193
6.3.4	Integrated intensity modulators . . . . .	194
6.3.5	Electro-optic directional couplers . . . . .	195

6.4	Applications of waveguide optics . . . . .	196
6.4.1	Waveguide optics in optical interconnects . . . . .	196
6.4.2	Waveguide optical sensors . . . . .	199
6.5	Glossary . . . . .	202
6.6	List of new symbols . . . . .	203
6.7	Exercises . . . . .	204
<b>7</b>	<b>Microoptical systems</b> . . . . .	<b>207</b>
7.1	Systems integration . . . . .	208
7.1.1	MOEMS for optical systems integration . . . . .	208
7.1.2	Stacked optics . . . . .	211
7.1.3	Planar optics . . . . .	213
7.2	Imaging systems for optical interconnects . . . . .	215
7.2.1	Dilute arrays . . . . .	215
7.2.2	Conventional imaging . . . . .	217
7.2.3	Multichannel imaging system . . . . .	218
7.2.4	Hybrid imaging . . . . .	221
7.2.5	Integrated microoptical imaging systems . . . . .	222
7.3	Glossary . . . . .	226
7.4	List of new symbols . . . . .	227
7.5	Exercises . . . . .	228
<b>8</b>	<b>Optoelectronic devices and smart pixel arrays</b> . . . . .	<b>231</b>
8.1	Superlattices and multiple quantum wells . . . . .	231
8.1.1	Hetero-superlattices . . . . .	232
8.1.2	nipi-superlattices . . . . .	233
8.2	The SEED (self-electro-optic effect device) . . . . .	234
8.2.1	Structure and fabrication . . . . .	234
8.2.2	Energy dissipation and efficiency . . . . .	235
8.2.3	All-optical modulation . . . . .	236
8.2.4	S-SEED . . . . .	237
8.2.5	Performance of S-SEEDs . . . . .	237
8.3	Vertical cavity surface emitting lasers . . . . .	239
8.3.1	Structure and fabrication . . . . .	239
8.3.2	Mirrors and resonator . . . . .	242
8.3.3	I-V characteristics and efficiency . . . . .	244
8.3.4	Spectral characteristics and thermal effects . . . . .	245
8.3.5	Other material combinations . . . . .	246
8.4	Smart pixel arrays (SPAs) . . . . .	247
8.5	Glossary . . . . .	250
8.6	List of new symbols . . . . .	251
8.7	Exercises . . . . .	252

<b>9</b>	<b>Array illuminators</b>	<b>255</b>
9.1	Image plane array illumination . . . . .	257
9.1.1	Phase-contrast array illumination . . . . .	258
9.1.2	Multiple beam-splitting through aperture division . . . . .	262
9.1.3	Multiple beam-splitting through waveguide coupling . . . . .	262
9.2	Fresnel plane array illuminators . . . . .	263
9.3	Fourier plane array illuminators . . . . .	266
9.3.1	Dammann gratings . . . . .	267
9.3.2	Modifications of Dammann's design procedure . . . . .	271
9.3.3	Lenslet arrays as Fourier plane array illuminators . . . . .	273
9.3.4	Cascading of beam-splitter gratings . . . . .	275
9.4	Summary . . . . .	275
9.5	Glossary . . . . .	277
9.6	List of new symbols . . . . .	278
9.7	Exercises . . . . .	279
<b>10</b>	<b>Microoptical components for beam shaping</b>	<b>283</b>
10.1	Beam shaping from a general perspective . . . . .	285
10.2	Lateral laser beam shaping . . . . .	288
10.2.1	Collimation of astigmatic beams . . . . .	288
10.2.2	Beam shaping for laser machining . . . . .	291
10.2.3	Beam shaping for LIDAR . . . . .	293
10.3	Axial beam shaping . . . . .	294
10.4	Temporal beam shaping . . . . .	297
10.5	Multiple aperture beam shaping . . . . .	299
10.6	Intra-cavity beam shaping . . . . .	300
10.6.1	Intra-cavity beam shaping of individual laser beams . . . . .	300
10.6.2	Intra-cavity beam shaping of arrays of laser beams . . . . .	303
10.7	Glossary . . . . .	305
10.8	List of new symbols . . . . .	306
10.9	Exercises . . . . .	307
<b>11</b>	<b>Microoptics for optical information technology</b>	<b>313</b>
11.1	Optical information processing . . . . .	313
11.1.1	Analog information processing . . . . .	313
11.1.2	Digital optical information processing . . . . .	315
11.2	Optical interconnects . . . . .	315
11.2.1	Terminology . . . . .	316
11.2.2	Interconnect hierarchy . . . . .	318
11.2.3	Optical clock distribution . . . . .	322
11.3	Microoptics for optical data storage . . . . .	323
11.3.1	Basics of optical data storage . . . . .	324
11.3.2	Microoptics for read/write heads . . . . .	327

11.3.3	Volume optical memories . . . . .	334
11.4	Glossary . . . . .	340
11.5	List of new symbols . . . . .	342
11.6	Exercises . . . . .	343
<b>12</b>	<b>Further application areas of microoptics</b>	<b>351</b>
12.1	Microlens arrays for imaging . . . . .	352
12.2	Beam steering with microoptical components . . . . .	355
12.3	Microoptical sensors . . . . .	360
12.3.1	Shack-Hartmann wavefront sensor . . . . .	360
12.3.2	Confocal sensing using microoptics . . . . .	361
12.4	Microoptics for optical design . . . . .	364
12.4.1	Achromatic diffractive/refractive doublets . . . . .	364
12.4.2	Multi-order lenses . . . . .	366
12.4.3	Athermalization with hybrid elements . . . . .	368
12.5	Glossary . . . . .	371
12.6	List of new symbols . . . . .	372
12.7	Exercises . . . . .	373
	<b>Conclusion</b>	<b>379</b>
	<b>Abbreviations</b>	<b>381</b>
	<b>Solutions to exercises</b>	<b>383</b>